

IN THE CLAIMS

1. - 37. (Canceled)

38. (New) A method for producing an electron-emitting device, the device comprising a conductive film including an electron emission region, the method comprising:

a first detection step for detecting a position on a plane of a substrate, to which a liquid containing an element of the conductive film is to be ejected; and

an ejecting step for ejecting the liquid by an ink jet apparatus to the position on the plane of the substrate detected by the first detection step, wherein

the first detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

39. (New) A method for producing an electronic device comprising:

a first detection step for detecting a position on a plane of a substrate, to which a liquid containing an element of a material constituting the electronic device is to be ejected; and

an ejecting step for ejecting the liquid by an ink jet apparatus to the position on the plane of the substrate detected by the first detection step, wherein

the first detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the first detection step.

40. (New) The method according to claim 38, wherein
the ejection of the ink by the ink jet apparatus is performed while moving, relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used in the first detection step.

41. (New) The method according to claim 40, further comprising a second detecting step for detecting at least one predetermined attribute of the liquid ejected by the ink jet apparatus.

42. (New) The method according to claim 41, wherein
the second detection step is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the second detection step.

43. (New) The method according to claim 39, wherein

the ejection of the ink by the ink jet apparatus is performed while moving, relatively to the substrate, both of the ejector of the ink jet apparatus and the detector used in the first detection step.

44. (New) The method according to claim 43, further comprising a second detecting step for detecting at least one predetermined attribute of the liquid ejected by the ink jet apparatus.

45. (New) The method according to claim 44, wherein
the second detection is performed while moving, relatively to the substrate, both of an ejector of the ink jet apparatus and a detector used in the second detection step.